

Title (en)

METHOD FOR STRUCTURING METAL BY MEANS OF A CARBON MASK

Title (de)

VERFAHREN ZUR METALLSTRUKTURIERUNG MITTELS KOHLENSTOFF-MASKE

Title (fr)

METHODE POUR STRUCTURER UN METAL A L'AIDE D'UNE MASQUE DE CARBONE

Publication

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Application

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Abstract (en)

[origin: WO2004008520A1] The invention relates to a method for structuring metal, in which at least one metal layer (2), e.g. made of aluminum, is deposited on an Si substrate (1) by means of a deposition method, whereupon an etching mask is produced on said metal layer (2) that is subsequently structured by means of etching, preferably plasma etching. The aim of the invention is to create a simplified method for structuring metal, which ensures sufficient passivation of the etched metal structures during the etching process by using simple means. Said aim is achieved by the fact that a hard mask layer is deposited on the previously deposited metal layer (2) that is to be structured, said hard mask layer being in the form of a carbon layer (3) on which a resist (5) is deposited. The carbon layer is structured by stripping once the resist has been structured so as to form a carbon mask. The metal layer is then etched with the carbon mask defining the structures thereof while passivating the side walls, whereupon the masks are stripped.

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